

Title (en)  
MICROMIRROR SYSTEMS

Title (de)  
MIKROSPIEGELSYSTEME

Title (fr)  
SYSTEMES DE MICROMIROIRS

Publication  
**EP 1588202 A4 20071010 (EN)**

Application  
**EP 03774800 A 20031010**

Priority  

- US 0332348 W 20031010
- US 26979602 A 20021011
- US 26976302 A 20021011
- US 26947802 A 20021011

Abstract (en)  
[origin: WO2004034103A2] Micromirror devices, especially for use in digital projection are disclosed. Other applications are contemplated as well. The devices employ a superstructure that includes a mirror supported over a hinge set above a substructure. Various improvements to the superstructure over known micromirror devices are provided. The features described are applicable to improve manufacturability, enable further miniaturization of the elements and/or to increase relative light return. Devices can be produced utilizing the various optional features described herein, possibly offering cost savings, lower power consumption, and higher resolution.

IPC 8 full level  
**G02B 7/182** (2006.01); **G02B 17/06** (2006.01); **G02B 26/00** (2006.01); **G02B 26/08** (2006.01); **G02B 26/12** (2006.01); **G02B 27/18** (2006.01)

IPC 8 main group level  
**G02B** (2006.01)

CPC (source: EP)  
**G02B 26/0841** (2013.01)

Citation (search report)  

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- [X] US 6028689 A 20000222 - MICHALICEK M ADRIAN [US], et al
- [A] US 2002071171 A1 20020613 - GREYWALL DENNIS S [US]
- See references of WO 2004034103A2

Designated contracting state (EPC)  
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HU IE IT LI LU MC NL PT RO SE SI SK TR

DOCDB simple family (publication)  
**WO 2004034103 A2 20040422**; **WO 2004034103 A3 20050811**; AU 2003282611 A1 20040504; CA 2502298 A1 20040422; EP 1588202 A2 20051026; EP 1588202 A4 20071010; JP 2006502449 A 20060119

DOCDB simple family (application)  
**US 0332348 W 20031010**; AU 2003282611 A 20031010; CA 2502298 A 20031010; EP 03774800 A 20031010; JP 2004543736 A 20031010